

Title (en)  
PVD VACUUM COATING UNIT

Title (de)  
PVD - VAKUUMBESCHICHTUNGSANLAGE

Title (fr)  
APPAREIL DE REVÊTEMENT SOUS VIDE PAR DPV

Publication  
**EP 2220265 A1 20100825 (DE)**

Application  
**EP 08856536 A 20081117**

Priority  
• CH 2008000485 W 20081117  
• CH 18902007 A 20071206

Abstract (en)  
[origin: WO2009070903A1] A vacuum coating unit contains a reactive gas inlet (12), at least one PVD coating source (8, 21) having a sheet-like cathode (11) and a substrate carrier (6) containing a plurality of substrates (7), where the substrate carrier (6) forms a two-dimensional horizontal extension and is positioned between at least two PVD coating sources and the plurality of substrates (7) are cutting tools having at least one cutting edge (E) in the peripheral region of the sheet-like substrate (7) and are distributed in a plane of the two-dimensional extension of the substrate carrier (6), where the substrate carrier (6) is positioned in a horizontal plane (3) in the vacuum process chamber (1) at a spacing between the sheet-like cathodes (11) of the at least two PVD coating sources (8, 21) in such a way that at least a part of each of the at least one cutting edge (E) contains an active cutting edge (E') which is at all times exposed in direct line of sight to at least one of the cathodes (11) of the PVD coating sources (8, 21).

IPC 8 full level  
**C23C 14/32** (2006.01); **C23C 14/50** (2006.01)

CPC (source: EP US)  
**C23C 14/325** (2013.01 - EP US); **C23C 14/50** (2013.01 - EP US); **C23C 14/505** (2013.01 - EP US)

Citation (search report)  
See references of WO 2009070903A1

Citation (examination)  
• JP 2000141108 A 20000523 - HITACHI TOOL ENG  
• US 2005056565 A1 20050317 - OLORE PAUL [US], et al

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Designated extension state (EPC)  
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DOCDB simple family (publication)  
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SG 10201604607P A 20081117; SG 2012089439 A 20081117; TW 97147045 A 20081204; US 27041508 A 20081113